



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

SUH, Nam P. et al.

Application No.:

10/029,158

Filed:

December 21, 2001

For:

Apparatus and Method for Chemical
Mechanical Polishing of Substrates

Examiner:

Maurina T. Rachuba

Art Unit:

3723

Confirmation No.:

5210

Date: December 13, 2005

Mail Stop PETITION

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

PETITION FOR CHANGE IN ORDER OF INVENTORS

Sir:

In accordance with MPEP § 605.04(f) and under the provisions of 37 C.F.R. § 1.182, Applicants hereby petition to change the order of names of the joint inventors of the above-identified application. Specifically, Applicants request that the order of inventors' names be changed to the following order:

Adjustment date: 03/09/2006 CKHLOK
12/16/2005 SFELEKE2 00000085 10029158
04 FC:1464 -130.00 OP

03/09/2006 CKHLOK 00000005 502319 10029158
01 FC:1462 270.00 DA 130.00 OP

- 1.) Jason Melvin;
- 2.) Nam P. Suh; and
- 3.) Hilario L. Oh

Accompanying this petition is a check in the amount of \$130.00 to cover the petition fee as set forth in 37 C.F.R. § 1.17(h).

The Commissioner is hereby authorized to charge any underpayment of the following fees associated with this communication, including any necessary fees for extension of time and for the presentation of extra claims, or credit any overpayment to Deposit Account No. 50-2319 (Our Order No. A-69175-1/MSS (463035-650)).

12/16/2005 SFELEKE2 00000085 10029158

04 FC:1464

130.00 OP

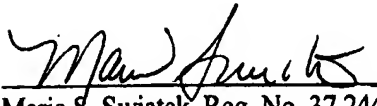
PATENT

Attorney Docket No. A-69175-1/MSS (463035-650)
U.S. Serial Application No. 10/029,158

Respectfully submitted,

Date: December 13, 2005

By:


Maria S. Swiatek, Reg. No. 37,244

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